



180/3  
PATENT

**IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE**

Applicant: Hyug-Jin Kwon  
Serial No.: 10/615,062  
Filed: July 8, 2003  
Title: BATCH TYPE ATOMIC LAYER  
DEPOSITION APPARATUS  
AND IN-SITU CLEANING  
METHOD THEREOF  
Group Art Unit: 1763  
Examiner: Sylvia MacArthur  
Attorney Docket No.: 29926/39496

I hereby certify that this paper is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450, on April 24, 2006.

  
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Attorney for Applicant

**AMENDMENT "B" AND  
SUPPLEMENTAL RESPONSE TO OFFICIAL ACTION**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Dear Sir:

A complete response to the non-final official action dated December 30, 2005, was submitted to the U.S. Patent and Trademark Office on March 30, 2006. In supplemental response to the December 30, 2005, official action, please amend the above-identified patent application as set forth herein. The amendments and remarks presented herein supplement the remarks previously submitted on March 30, 2006, and should be considered along with the previous remarks.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.